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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): T. KAJI, et al  
Serial No.: 10/090,759  
Filed: September 11, 2003  
For: EMISSION SPECTROSCOPIC PROCESSING APPARATUS  
AND PLASMA PROCESSING METHOD USING IT

**REAFFIRMATION OF CLAIM FOR PRIORITY**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

September 11, 2003

Sir:

Under the provisions of 35 USC §119 and 37 CFR §1.55, Applicants hereby claim the right of priority based on Japanese Patent Application No. 2001-364626, filed in Japan on November 29, 2001.

The certified copy of the above-referred to Japanese Patent Application was filed on April 29, 2002 in prior application Serial No. 10/090,759, filed March 6, 2002.

Respectfully submitted,



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